PATENT Customer No. 22,852 Attorney Docket No. 04329.2858-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re A | application of: |) |
|---------|---|----------------------------------|
| Kei W | ATANABE, et al. |) Parent Group Art Unit: 2812 |
| - | Application No.: 10/201,892 filed 5, 2002 |) Parent Examiner: Nguyen, Ha T. |
| Filed: | Herewith |) |
| For: | SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF |))) |
| P.O. B | nissioner for Patents Sox 1450 ndria, VA 22313-1450 | |
| Sir: | | |

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), Applicants bring to the attention of the Examiner the documents listed on the attached PTO-1449. Applicants file this Information Disclosure Statement together with the above-referenced divisional application.

Applicants previously submitted copies of the listed documents, or they were cited by the Examiner in prior application No. 10/201,892, filing date July 25, 2002, upon which Applicants rely for the benefits provided in 35 U.S.C. § 120. Applicants respectfully request that the Examiner consider the listed documents, and indicate that they were considered by making appropriate notations on the attached form.

The following is a concise statement of relevance of each of the non-English language documents:

FINNEGAN HENDERSON FARABOW GARRETT & DUNNERLLP

1300 l Street, NW Washington, DC 20005 202.408.4000 Fax 202.408.4400 www.finnegan.com 1. Japanese Patent Application Publication No. 3234121 - discloses a SiOF film

which has characteristic network structure.

2. Japanese Patent Application Publication No. 6-302704 - discloses a similar wiring

structure to that of the above-identified document JP 3234121, (see Figure 3).

This submission does not represent that a search has been made or that no better art exists, and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and Applicants determine that the cited documents do not constitute "prior art" under United States law, Applicants reserve the right to present to the Office the

relevant facts and law regarding the appropriate status of such documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be

applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the

fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW, GARRETT & DUNNER, L.L.P.

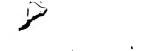
Dated: September 24, 2003

David M. Longo

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INFORMATION DISCLOSURE CITATION

| Atty. Docket No. | 04329.2858-01 | Div. of Serial No. | 10/201,892 |
|------------------|----------------------|--------------------|------------|
| Applicant | Kei WATANABE, et al. | | |
| Filing Date | Herewith | Prior Group: | 2812 |

| U.S. PATENT DOCUMENTS | | | | | | |
|-----------------------|--------------------|------------|------------------|-------|--------------|----------------------------|
| Examiner Initial* | Document Number | Issue Date | Name | Class | Sub Class | Filing Date If Appropriate |
| | 6,008,120 | 12/1999 | Lee | | | |
| | 5,429,995 | 07/1995 | Nishiyama et al. | | | |
| | 6,057,251 | 05/2000 | Goo et al. | | | |
| | 6,255,233 | 07/2001 | Smith et al. | | | |
| | 6,429,105 | 08/2002 | Kunikiyo | | | |
| | 6,437,424 | 08/2002 | Noma et al. | | | |
| | | | | | | |

| • | Document Number | Publication Date | Country | Class | Sub Class | Translation Yes or No |
|---|--------------------|---------------------|---------|-------|--------------|--------------------------|
| | 6-302704 | 10/1994 | Japan | | | No |
| | 3234121 | 09/2001 | Japan | | | No |

| OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | |
|--|--|--|--|--|
| Richard Swope, et al., "Improvement of Adhesion Properties of Fluorinated Silica Glass Films by Nitrous Oxide Plasma Treatment," Journal of the Electrochemical Society, Vol. 144, No. 7, July 1997, pp. 2559-2564 | | | | |
| Kwon et al., "Semiconductor Device Having Improved Metal Line Structure and Manufacturing Method Therefor," U.S. Application Publication No. 2001/0006255 A1, published July 5, 2001 | | | | |
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| | | | | |

| Examiner | | Date Considered | |
|---|--|--|--|
| *Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | |
| Form PTO 1449 Patent a | | d Trademark Office - U.S. Department of Commerce | |